

Part Number

Customer

| Category | Parameter | Specification | Measurement Method |
|---------------|-------------------------------------|-----------------------|------------------------------|
| OverallWafer | 1.0 Diameter | 150.00 +/- 0.50 mm | WaferVendor |
| | 2.0 Primary Flat Length | 57.50 +/- 2.50 mm | Wafer Vendor |
| | 3.0 Primary Flat Orientation | {110} +/- 0.5 degree | Wafer Vendor |
| | 4.0 Growth Method | CZ | Wafer Vendor |
| | 5.0 Type | P | Wafer Vendor |
| | 6.0 Dopant | Boron | Wafer Vendor |
| | 7.0 Resistivity | 10~30 ohm cm | Wafer Vendor |
| | 8.0 Overall Thickness | 1,100.00 +/- 25.00 um | Wafer Vendor |
| | 9.0 Total Thickness Variation (TTV) | <10.00um | Guaranteed by process |
| | 10.0 Orientation | <100> +/-0.5 | Wafer Vendor |
| | 11.0 Back Surface Quality | Lapped/Etched | Wafer Vendor |
| | 12.0 Front Surface Quality | Prime | Wafer Vendor |
| | 13.0 Edge Chips | None | Bright Light 100% (note 2) |
| DeviceSilicon | 15.0 Haze | None | Bright Light, 100% (note 2). |
| | 16.0 Scratches | None | Bright Light, 100% (note 2). |

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| Shipping Details | Wafer per box : | Max 25 |
| | Packaging : | Taped Polypropylene Wafer Box Empak, Ultrapak, 150.00mm Antistatic Double Bagging |
| | Lot Shipment Data | Device Thickness Bow / Warp Data Handle and SOI Thickness |



Explanatory Notes 1. Microscope inspection performed using microscope scan as below. 5x objective.

2. All bright light inspections performed exclude all wafer area outside the edge exclusion defined in Overall Wafer, Edge Exclusion. High intensity bright lamp inspection as per ASTM F523.

3. 9 point measurement are as shown in the diagram below:



Additional Information